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| Form 1449* | Atty. Docket No.: 303.098US4 | Serial No. Unknown |
| INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary) | Applicant: Yong-Jun Hu | |
| | Filing Date: Herewith | Group: Unknown |

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| Examiner | JOSEPH NEUVEN | Date Considered | 10/21/01 |
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*Substitute Disclosure Statement Form (PTO-1449)

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